

Notice of References Cited	Application/Control No. 10/751,138		Applicant(s)/Patent Under Reexamination HA ET AL.	
	Examiner Bret Chen		Art Unit 1792	Page 1 of 1

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*	D	US-5,271,972	12-1993	Kwok et al.	427/579
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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